

a priority from U.S. Patent Application No. 09/114,105, filed July 11, 1998; which application is a continuation-in-part of U.S. Patent Application No. 08/990,107, filed December 15, 1997, all of which are herein incorporated by reference in their entirety.

REMARKS

The above amendment has been made merely to clarify the priority claims in the subject application. No new matter has been added by way of this amendment. The Examiner is encouraged to contact Paul Parker at (206) 287-3258 should there be any questions regarding this amendment.

Respectfully submitted,

Perkins Coie LLP



Paul T. Parker
Registration No. 38,264

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Enclosure:

Appendix (Marked-up version of specification)

PERKINS COIE LLP
P. O. Box 1247
Seattle, Washington 98111-1247
(206) 583-8888
FAX: (206) 583-8500



Appendix – Specification Marked to Show Changes

~~The present~~This application is a continuation of ~~prior~~ International Application No. PCT/US99/15567, which was filed in English on July 9, 1999 and published as International Publication No. WO 00/02808,; which in turnapplication claims priority to continuation-in-part of from U.S.S.N. 08/990,107, filed December 15, 1997, titled "Semiconductor Processing Apparatus Having Linear Conveyor System" and U.S.S.N. U.S. Application No. 09/114,105, filed July 11, 1998 entitled "Improved Robot for Microelectronic Workpiece Handling"; which application is a continuation-in-part of U.S. Patent Application No. 08/990,107, filed December 15, 1997, all of which are herein incorporated by reference in their entirety. ~~The entire disclosures of both of the prior applications, as well as International Publication No. WO00/02808, are incorporated herein by reference.~~